## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:	)	Confirmation No.: 2015
Koichiro TANAKA et al.	)	Examiner: Abdulfattah Mustapha
Serial No. 10/582,614	)	Group Art Unit: 2812
Filed: June 12, 2006	)	
For: LASER IRRADIATION METHOD,	)	
LASER IRRADIATION APPARATUS,	)	
AND METHOD FOR	)	
MANUFACTURING	)	
SEMICONDUCTOR DEVICE	)	

## **AMENDMENT**

Honorable Commissioner of Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In response to the Official Action dated April 15, 2009, please consider the following amendments and remarks in connection with the above-identified application.

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.